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Boron Characterization in Intermetallic Bulk or Thin Film Alloys using Scanning Electron Microscopy and Electron **Probe Microanalysis**

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Scanning Electron Microscopy Facilities and Electron Probe Micro-Analyser







Scanning Electron Microscope - JEOL 840A Stability - Performance - Productivity SAMx Energy Dispersive X-ray Spectroscopy (EDX- Si [Li])

Field Emission Gun Scanning Electron Microscope (FESEM) - ZEISS ULTRA+, BRUKER Energy Dispersive X-ray Spectrometry (SDD), Electron BackScatter Diffraction (EBSD) OXFORD





Several Sm-Co-B samples were prepared by induction melting in a pure argon gas atmosphere. Sm-Co-B ingots were sealed in a quartz tube and annealed for three weeks at 900 $^{\circ}$ C.

RE-M-B alloys are very sensitive to oxidation, which complicates sample preparation for microscopy. Indeed, it was very challenging to carry out efficient preparation without creating damage or causing oxidation. Water-free lubricant is preferable, so absolute ethanol and glycol were used. To limit oxidation, samples were prepared just prior to observation and transport in a vacuum desiccator. Polishing was carried out using grinding paper and then polishing cloth with 0.25 μ m alumina or diamond particles.

Electron Probe Micro-Analyser (EPMA - JEOL 8800) Equipment: 5 wavelength dispersive x-ray spectrometers (WDS) each with two crystals 1: PETH / LDE3H 2: TAP / LDE1H 3: LED2 / LDE2H 4: PETJ / LiFH 5: PETH / LiF (Xe)

Thin films analysis based on EDX and WDX measurements

Hard magnetic films have many potential applications in micro-systems and serve as model systems to study the physics of magnetisation reversal in these technologically important materials. The functional properties of hard magnetic materials, in particular their resistance to demagnetisation (i.e. their coercivity), depend critically on their microstructure.

Films of NdFeB were made by high rate triode sputtering [5]. Buffer and capping layers such as Ta are used to prevent interdiffusion into the substrate and oxidation from the atmosphere, respectively. Films were characterised by cross-sectional SEM imaging coupled with Energy or Wavelength Dispersive Spectrometries (EDX & WDX). Boron content was determined with EPMA measurements (LDE3H), Nd and Fe with EDX and PETH or LiF crystals.

Changing the energy of the incident electrons varies the volume of the electron-matter interaction in the sample : at low beam voltage for example, the upper layers are favoured compared to buried layers and the substrate. A multi-layer sample is characterized by doing x-ray analyses at different beam voltages. The results are treated by off-line calculation software packages (STRATAgem / SAMx [6]). The calculations use the nominal layer architecture as starting input, estimating fluorescence and absorption for the given geometry. At the end of an iteration process, curves of predicted relative intensities corresponding to the chemical compositions and thicknesses found are drawn and compared with the experimental data to validate the analysis.



For these experiments, Mo capping layers were used since the mass absorption coefficient of the K α line (183eV) of Boron by Ta is very high. The half-value layer for B absorption by Ta and Mo is 20nm (M.A.C.= 20,820 cm²g⁻¹) and 130nm (M.A.C.= 5,238 cm²g⁻¹), respectively. The absorption for Fe-k α (6.4keV) and Nd-L α (5.23keV) are weak (M.A.C. less than 500 cm^2g^{-1}).

(4 < y/x < 5); characterisation was carried out on samples in the Thin film specimen : Si / Mo / Nd_xFe_yB_z / Mo as-deposited state (i.e., not annealed).





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1	3,316	56,824	39,	86			1	19,968	4 62,773	3 17,258	3	
2	3,985	56,36	39,	655			2	23,201	8 60,1970	5 16,600	6	
3	3,391	56,939	39,	67			3	20,319	1 62,5890	5 17,091	2	
4	3,879	56,727	- 39,	394			4	22,6604	4 60,7929	9 16,546	7	
5	3,667	56,83	39,	503			5	21,656	3 61,5690	5 16,774	0	
Minimum	3,316	56,36	39,	394			Minimum	19,968	4 60,1976	5 16,546	7	
Maximum	3,985	56,939	39	86			Maximum	1 23 201	8 62 773	3 17,258	3	
Average	3,65	56,74	39,	62			Average	21,56	61,58	16,85		
NO. 1	B 3,66	Total 99,88		3	\bigwedge			NO. 1 2	в 21,654	16,785	5m 61,561	
No.	B	Total		3,3	1 mar			NO.	В	Co	Sm	2. 2. 2. 12
1	3,66	99,88		3				1	21,004	16,783	61,301	
2	3,74	99,96		25				4	21,983	16,714	61,303	
3	3,73	99,95	≥	2,3				3	21,948	16,722	01,33	
4	3,7	99,92	<u>.</u>	24				4	21,828	16,748	01,425	
5	3,71	99,93	Ë	~		Δ [2	21,885	16,735	01,38	
6	3,72	99,94	e	1,5		<u> </u>		0	21,932	10,725	01,343	
 Minimum	3 66	99 88	Ē	1				Minimum	21,654	16,714	61,303	
Maximum	3 74	99.96		· · •				Maximum	21,983	16,785	61,561	
Average	3,71	99.93		0.5				Average	21,87	16,74	61,39	
arei uge	2,12											
				0	50	100	150					
				· ·	Den	th (nm	1)					
							.,					

NO.

B-by

difference

CO

Area-peak factors, relative to elemental boron (asterisk). Solid circles indicate that no dependence on crystallographic orientation exists. Bars indicate the variation in APF with peak position (crystallographic orientation)

The values obtained at 15kV for Sm₂CoB₉ & Sm₅Co₂₁B₄ phases are dispersed in a range about wt%=0.2 and wt%= 0.5. No changes have occurred despite the two steps calculation. It could be due to several things: difference between the shape of the Boron peak of the standard and the sample, the primaries phases $Sm_2CoB_9 \& Sm_5Co_{21}B_4$ could be unstable and split into two phases (the average of the results in the Sm₅Co₂₁B₄ stayed at the expected value) or could not exist (Sm_2CoB_9) ! For others phases the computation focus to 0.1%

B-by difference

CO

Sm

Estimates of the film thickness and composition (iron relative to neodymium) made with both Si(Li) and EPMA analysis are in good agreement with direct observation / measurements. However, for the boron content, the estimate is greater than expected. Several reasons could explain this. For these runs, no energy filter on the LDE3H spectrometer was used. The Molybdenum layer also creates a convolution between the B-Ka and Mo-M peaks, and no overlapping correction was applied. Therefore, a weak error occurred but with the M.A.C. and the $\Phi(\rho z)$ correction, the error increases.

[1]: Y.Chen et al., Journal of Alloys and Compounds288 (1999) 170–172 Neel.cnrs.fr - 2017 [2]: P. Villars, L.D. Calvert, Peasons Handbook of Crystallographic Data For Intermetallic Phases, 2nd ed., ASM, Materials Park, Ohio, 199 **European Microbeam** [3]: Casino v2.4.8.1, Drouin D., Réal Couture A., Gauvin R., Hovington P., Horny P. Demers H., Joly D., Drouin P., Poirier-Demers N., 2011 [4] : Daoudi et al., "New K-shell fluorescence yield for element with $3 \le Z \le 99$ ", J. of the Korean Physical Society vol 9, Nov. 2015 **Analysis Society** [5]: N.M. Dempsey, A. Walther, F. May, D. Givord, K. Khlopkov, O. Gutfleisch, Appl. Phys. Lett. 90 (2007)092509 [6] : Stratagem v2.8, "Thickness and compositional thin film analysis", Pouchou J.L., Pichoir F [7]: Bastin, G. F., & Heijligers, H. J. M. (1990). "Quantitative electron probe microanalysis of ultralight elements (boron-oxygen)". Scanning, 12(4), 225-236. DOI: 10.1002/sca.4950120408 EMAS 2017 - 15th European Workshop on MODERN DEVELOPMENTS AND APPLICATIONS IN MICROBEAM ANALYSIS